

EAST Search History

EAST Search History (Prior Art)

| Ref # | Hits | Search Query | DBs | Default Operator | Plurals | Time Stamp |
|-------|------|---|---|------------------|---------|---------------------|
| L1 | 27 | (stage table wst) near (substrate wafer object) and (lyophilic hydrophilic liquidphilic philic affinity) near (recover\$1) | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2010/08/13 16:42 |
| L2 | 57 | (stage table support chuck) near (substrate wafer object workpiece) same (lyophilic hydrophilic liquidphilic philic affinity) with (recover\$3 remov \$3) | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2010/08/13 16:42 |
| L3 | 20 | (stage table support chuck) near (substrate wafer object workpiece) same (lyophilic hydrophilic liquidphilic philic affinity) with (recover\$3 remov \$3) and (\$5lithograph\$2 exposure).ti. | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2010/08/13 16:42 |

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|----|----|--|---|----|----|---------------------|
| L4 | 0 | (stage table support chuck) near (substrate wafer object workpiece) same (lyophilic hydrophilic liquidphilic philic affinity) with (protrud\$3 overhang\$3) and (\$5lithograph\$2 exposure).ti. | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2010/08/13 16:42 |
| L5 | 42 | (stage table support chuck) near (substrate wafer object workpiece) same (protrud\$3 overhang\$3) same (recover\$3 remov \$3) and (\$5lithograph\$2 exposure).ti. | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2010/08/13 16:42 |
| L6 | 36 | (stage table support chuck) near (substrate wafer object workpiece) same (protrud\$3 overhang\$3) same (recover\$3 remov \$3) with (liquid fluid immersion) and (\$5lithograph \$2 exposure).ti. | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2010/08/13 16:42 |

8/ 13/ 2010 4:43:14 PM

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